Special Issue

III-V Optoelectronics and Semiconductor Process Technology

Message from the Guest Editors

The Special Issue "**III-V Optoelectronics and Semiconductor Process Technology**" in the Journal ***Micromachines*** invites high-quality contributions from both academia and industry. The topics covered include the epitaxial growth and fabrication of III-V semiconductors, device design and characterization, novel device concepts, and process technology for III-V-based devices. The Special Issue also covers the use of III-V materials in various applications, such as LEDs, lasers, photovoltaic cells, and sensors. We look forward to receiving your submissions to this Special Issue.

Guest Editors

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